

Patent Assignment Abstract of Title

Total Assignments: 1**Application #:** 09993223 **Filing Dt:** 11/26/2001**Patent #:** NONE**Issue Dt:****PCT #:** NONE**Publication #:** 20020081857**Pub Dt:** 06/27/2002**Inventor:** Kenichi Kurisu**Title:** Etching method for ZnSe polycrystalline substrate**Assignment: 1****Reel/Frame:** 012327/0201 **Received:**
12/04/2001**Recorded:**
11/26/2001**Mailed:**
01/23/2002**Pages:**
2**Conveyance:** ASSIGNMENT OF ASSIGNORS INTEREST (SEE DOCUMENT FOR DETAILS).**Assignor:** KURISU, KENICHI**Exec Dt:** 11/13/2001**Assignee:** SUMITOMO ELECTRIC INDUSTRIES, LTD.
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Search Results as of: 2/4/2003 1:45:12 P.M.

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Web interface last modified: Oct. 5, 2002